

IN THE CLAIMS:

Please enter the following listed claims:

1 (currently amended): An integrated circuit semiconductor memory device provided with a semiconductor fin comprising:

 a substrate;

 a first dielectric layer covering a first portion of said substrate, said first dielectric layer being absent from a second portion of said substrate;

 a second dielectric layer having a property different from said first dielectric layer, said second dielectric layer at least partly covering said second portion of said substrate;

 a source region formed in a first doped region on said first dielectric layer;

 a drain region formed in a second doped region on said first dielectric layer; and

 a gate formed over said second dielectric layer and between said first and second doped regions,

~~wherein said property of said second dielectric layer provides a gate capacitance of said gate with respect to said substrate that is greater than a theoretical capacitance of a gate formed over said first dielectric layer on said substrate,~~

wherein said substrate has an upwardly facing first surface at an upper level and an upwardly facing second surface at a lower level, said first dielectric layer being a dielectric layer formed on said first surface, said second dielectric layer being a dielectric layer formed on said second surface, and said fin being formed over said first dielectric layer.

2 (original): The device of claim 1, wherein said device is RAM.

3 (original): The device of claim 1, wherein said device is SRAM.

4 (original): The device of claim 1, wherein said device includes a FET.

5 (original): The device of claim 4, wherein said FET is a FinFET.

6 (original): The device of claim 5, wherein said first dielectric layer is a buried oxide layer and said second dielectric layer is a thin oxide layer providing less insulating effect than said buried oxide layer, said gate being capacitively coupled to said substrate.

7 (original): The device of claim 6, wherein a fin of said FinFET is formed over said buried oxide layer.

8 (original): The device of claim 5, wherein said device further comprises a fin and a gate dielectric layer between said gate and said fin, wherein said second dielectric layer has less leakage than said gate dielectric.

9 (canceled)

10 (original): The device of claim 9, wherein said first dielectric layer is a buried oxide layer and said second dielectric layer is a thin oxide layer.

11 (original): The device of claim 1, wherein said first dielectric layer is a buried oxide layer and said second dielectric layer is a thin oxide layer providing less insulating effect than said buried oxide layer, said gate being capacitively coupled to said substrate.

12 (original): The device of claim 1, wherein said device further comprises a fin and a gate dielectric layer between said gate and said fin, wherein said second dielectric layer has less leakage than said gate dielectric.

13 (original): The device of claim 1, wherein said substrate has an upwardly-facing first surface at an upper level and an upwardly-facing second surface at a lower level, said first dielectric layer being a dielectric layer formed on said first surface, said second dielectric layer being a thin dielectric layer formed on said second surface, and a fin of said FinFET being formed over said buried layer.

14 (original): The device of claim 12, wherein said first dielectric layer is a buried oxide layer and said second dielectric layer is a thin oxide layer.

15 (new): The device of claim 1, wherein said property of said second dielectric layer provides a gate capacitance of said gate with respect to said substrate that is greater than a theoretical capacitance of a gate formed over said first dielectric layer on said substrate.